I2FSR - Improved Flared Silicon Ridge

Line with sharp, overhanging edges.

Specifications

Material Silicon coated with Siliconnitride

Width of line ~ 2 µm

Depth of line $> 4 \mu m$

Overhang > 250 nm

Overhang slope angle ~ 35°

Top corner radius < 10 nm

Edge roughness < 10 nm

Probe tip characterizers are used to check the shape and the dimension of the probe tip.

Each cell is numbered, which facilitates recalibration at the identical position.

Layout:

81 cells on 1 x 1 mm area, on 6 x 6 mm silicon chip